

Notice of References Cited

Application/Control No.

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Applicant(s)/Patent Under

Reexamination

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Examiner

COLIN KREUTZER

Art Unit

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*	B US-2004/0004771 A1	01-2004	Omura, Yasuhiro	359/649
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L	US-			
M	US-			

FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a))
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